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1	Effects of helium irradiation on fine grained β -SiC synthesized by Spark Plasma Sintering
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8	
9	Key words : ceramic; irradiation; helium; nuclear; SiC

10 Abstract

11 Silicon carbide has a high resistance to irradiation making it a material of choice for use in the nuclear reactors. In this work, we focus on experiments involving implantation of 30 keV ³He ions at room temperature 12 13 (RT) in sintered β -SiC. Helium is produced in large quantities in fission and fusion reactors, and its accumulation 14 in materials can lead to the formation of bubbles. The irradiation induces structural modifications within the 15 material that can be coupled with changes in composition, especially at high fluence. Three ion fluencies are used 16 here: 5×10^{15} , 1×10^{17} and 1×10^{18} at.cm⁻². Structural damages are studied by electron microscopy and helium profiles are measured by nuclear reaction analysis (NRA). At 1x10¹⁸ at.cm⁻², helium bubbles are formed in the 17 implanted zone, which also undergoes strong oxidation. Surface blisters are also observed and helium 18 19 concentration threshold for bubble formation is estimated to about 4 at. % by correlating the MET observations with the results obtained by ion beam analysis. For the highest fluence, a residual concentration of 3.6×10^{17} at.cm⁻ 20 ² was measured just after implantation (instead of 1×10^{18} at.cm⁻²), which indicates a significant release of helium 21 by the material during the process. The link between the microstructural evolution of the material, its progressive 22 23 oxidation under beam and the release of helium is discussed. The very likely role played by the porosity on the 24 oxidation of the material under irradiation at RT is underlined. Finally, the results obtained here on silicon carbide are compared with those obtained on another ceramic (TiC) which does not amorphize in similar conditions. 25

26

1 Introduction

2 Nuclear industry is looking to develop new materials able to withstand increasingly hostile environments. 3 Because of its remarkable properties (creep and oxidation resistance [1-3], radiation tolerance [4-8]), silicon 4 carbide is under investigation as cladding with enhanced tolerance for light water reactors [9-16], as well as 5 cladding for GenIV nuclear plants [9-11, 17-18]. For nuclear fusion [9-10], the addition of SiC in the form of a 6 thin layer on the metallic structures (W [19] or Eurofer [20], i.e. Reduced Activation Ferritic Martensitic steel), 7 should enable better control of the tritium inventory (diffusion barrier limiting tritium losses). It should also 8 improve corrosion resistance in the case of SiC inserts in tritium blankets where the liquid metal, PbLi, circulates 9 [20]. For all the above-mentioned nuclear applications, the (n,α) nuclear transmutation reaction inevitably 10 introduces numerous atomic helium atoms in the SiC. The He/dpa production rate in SiC is reported to be 2.5 appm/dpa for typical fission neutron spectra [21-22]. In a fusion reactor, SiC will be exposed not only to a high 11 12 irradiation dose (up to 200 dpa), but also high helium generation rates, i.e. 70 appm/dpa in the reactor, 130 13 appm/dpa for the first wall [3, 23-25], and about 16,000 appm/yr at 10 MW/m2 [26]. A rapid calculation leads to 14 typical helium concentrations of the order of 0.05 at.% for fuel components in fission reactors and about 2.5 at.% 15 (and even greater) for structural materials in fusion reactors.

Linez et al. [27] have shown experimentally that helium preferentially occupies tetrahedral interstitial sites after implantation at room temperature in 6H-SiC. After annealing at 400 °C, a migration of helium to the silicon vacancies and silicon and carbon bi-vacancies is observed. Due to the low solubility of He atoms in SiC, a certain concentration of He atoms that are trapped in the matrix in the form of helium-vacancy clusters would form bubbles upon annealing [28-29]. These bubbles can cause degradation of the material properties [16, 30-31], such as the phenomenon of He embrittlement, microstructure evolution, blistering, volume swelling and deleterious effects on thermal properties.

23 In the absence of suitable fission or fusion neutron test facilities capable of achieving the high neutron 24 fluences expected in advanced reactors, ion implantation and irradiation techniques can be used to investigate the 25 effect of high helium content and high irradiation doses in SiC. Ion implantation with helium ions has two 26 advantages. First, it results in a well-known helium concentration profile. Secondly, the production and 27 accumulation of defects due to the implantation can lead to amorphization and chemical disordering, as well as 28 drive the nucleation and growth of helium bubbles. Using these techniques, the threshold for helium bubble 29 formation at room temperature has been determined by several authors [30, 32-35]. These concentrations vary 30 between 1.7 and 8.0 at. %. As an illustration, Zinkle et al. [30] observed bubble formation in 3C-SiC (β-SiC) at a 31 concentration of about 4 at. % after irradiation with a 1 MeV He⁺ ion beam at room temperature. This author also 32 conducted studies at higher fluence and was also able to observe the formation of blisters and the beginning of 33 exfoliation at a concentration of about 20 at. %. Using transmission electron microscopy (TEM), only nanobubbles 34 were revealed in this study which did not include complete chemical analyses (oxidation, composition evolution, 35 helium profiles). Note that SiC blistering under light ion implantation has been also extensively described for the 36 needs of smart cut treatments that typically combine irradiation and then annealing [36]. The dependence of SiC 37 radiation resistance on irradiation species was underlined by several authors [37-38]. For example, Jamison et al. 38 [38] showed that irradiation with 1 Mev Kr ions resulted in a lower dose to amorphization if compared with lighter 39 species.

1 β -SiC specimens were synthesized by spark plasma sintering (SPS) to obtain fine microstructures with 2 grain size below 100 nm. The synthesis and irradiation protocols are described in the first section. The second 3 section describes the modifications induced by helium irradiation. The phenomena observed are discussed in a 4 third section, which includes a comparison with previous results obtained on SiC [39] implanted with xenon, and 5 TiC [40] implanted with helium at comparable fluencies.

6 2. Experimental

SiC samples were obtained by Spark Plasma Sintering, starting from nanopowder synthetized by laser
pyrolysis. The complete protocol has been described extensively elsewhere and hence is not detailed here [39, 41].
Sintered bodies exhibit grains of size comprised between 20 and 130 nm, with an average grain size near 60 nm.
The relative density is found to be near 94 %, meaning that the material has some porosity that is visible on the
surface after polishing. A chemical analysis was done by Ion beam analysis and the final stoichiometry was found
to be SiC_{1.02}O_{0.1}. Thin cross sections were prepared by Focused Ion Beam (FIB) to allow TEM observations.

Three helium fluencies were used for implantation: 5×10^{15} at.cm⁻² (He beam current density i = 0.25) 13 μ A.cm⁻²), 1x10¹⁷ at.cm⁻² (i = 2.5 μ A.cm⁻²) and 1x10¹⁸ at.cm⁻² (i = 5 μ A.cm⁻²). Hereafter, these fluencies are termed 14 as Φ_1, Φ_2, Φ_3 respectively. The sample holder is kept cold during implantation by a circulation of water and helium 15 16 ions are accelerated to an energy of 30 keV under a vacuum of nearly 10^{-6} mbar. Damage and nominal He 17 concentrations were calculated using the Stopping Range of Ions in Matter (SRIM-2013) Monte Carlo computer 18 code [42]. DPA was calculated using the 'Quick' Kinchin-Pease option of SRIM for 1 000 000 ions with a 19 displacement energy of 35 eV for Si and 21 eV for C [43] with lattice and surface binding energies set to 0 eV. 20 The results are shown in Fig. 1. The dpa range commonly accepted in the literature as that corresponding to the 21 SiC amorphization threshold is also indicated in Fig. 1 [30]. Note that this threshold can vary according to 22 irradiation ion species, irradiation temperature and microstructure [44].

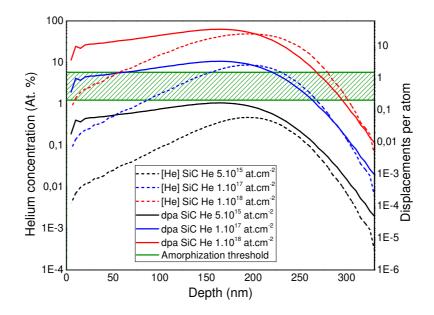
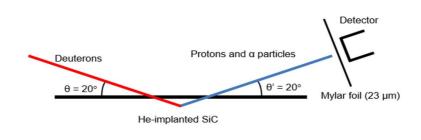


Figure 1: Helium depth profiles and corresponding dpa profiles, deduced from SRIM-2008[®] simulations, for the three fluences Φ_1 (low fluence), Φ_2 (intermediate fluence) and Φ_3 (high fluence).

After implantation, the helium content was determined using the ³He (d, p) ⁴He nuclear reaction characterized by a wide resonance centered on $E_d = 450$ keV [45]. The incident deuteron beam impinges on the sample surface at an angle of 20° (Fig. 2), and a mylar foil with a thickness of 23 µm is placed in front of a Si detector to block the forward scattered or recoiled particles, except protons and α particles from the ³He (d, p) α reaction. The incident deuteron energy was set at 0.6 MeV in order to reach 0.45 MeV around the maximum theoretical helium concentration.



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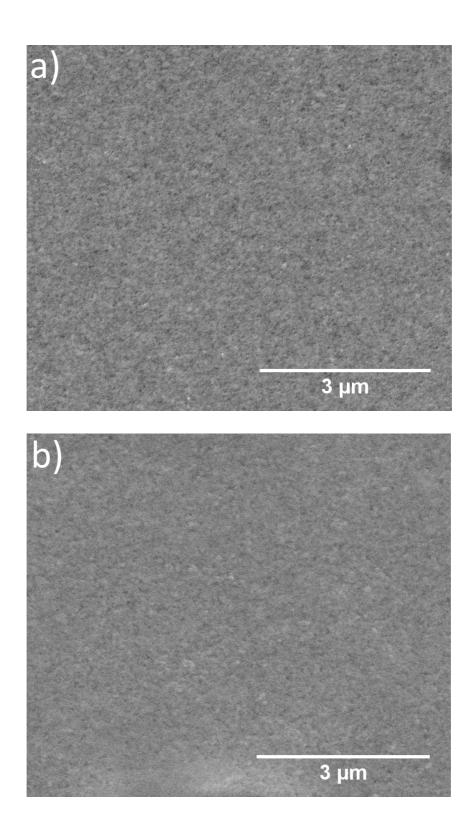
Figure 2: Geometry used for NRA analysis.

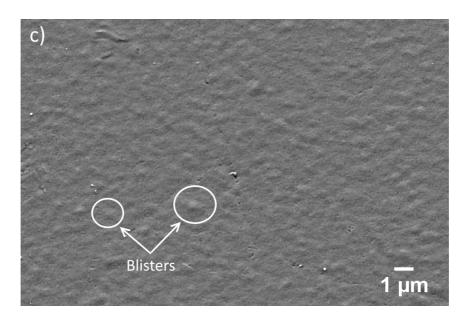
11 The evolution of the sample surface morphology was followed by SEM (FEI® Quanta 250 FEG ESEM).
12 Cross-sections prepared by FIB were observed by TEM (Jeol®2100F). Three modes were used for these
13 observations: Bright field, Selected Area electron diffraction (SAED) and Scanning TEM (STEM) with a High
14 Angle Annular Dark Field detector (HAADF), coupled with EDX analysis (elemental mapping).

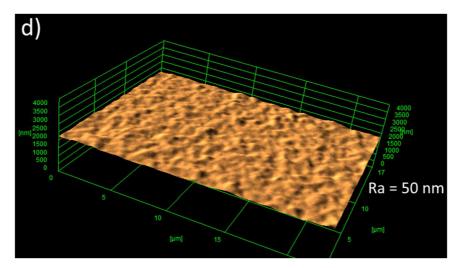
15 3. Results

16 3.1 Surface morphology and structure

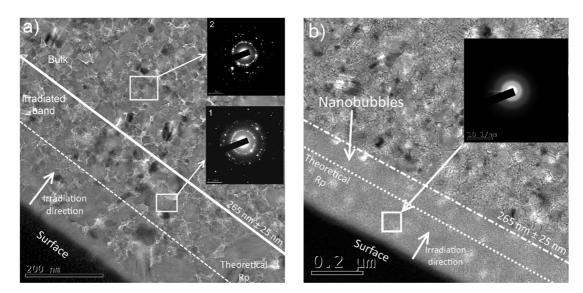
17 The surface of the SiC pellets was observed by SEM after ion implantation (Fig. 3). No visible 18 modification occurred after irradiation at Φ_1 and Φ_2 , and the images of the surface shown in Fig. 3a and 3b are 19 very similar to those obtained before irradiation. For Φ_3 , blisters of < 1 µm formed on the surface (Fig. 3c). 3D 20 analysis of the Φ_3 sample is shown in Fig. 3d (Zeiss® 3DSM software). An R_a value of 50 nm was found after 21 irradiation (about 10 nm before implantation). Thin sections of these samples were prepared by FIB and then 22 observed by TEM (Fig. 4).







3 Figure 3: SEM images of the SiC surface after RT helium implantation at $\Phi_1(a)$, $\Phi_2(b)$ and $\Phi_3(c)$. d) 3DSM analysis of the Φ_3 sample.





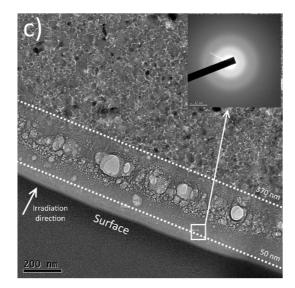
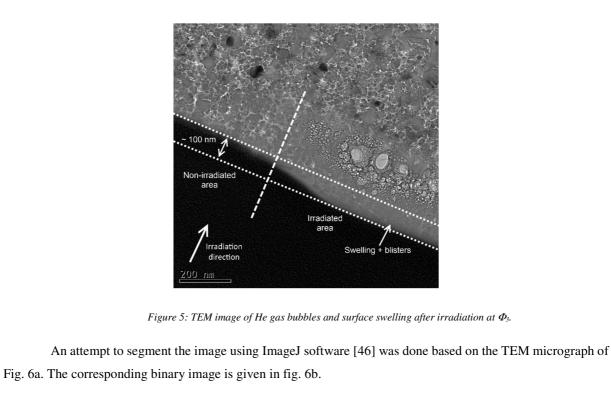




Figure 4: TEM image of the SiC sample after helium RT implantation at $\Phi_1(a)$, $\Phi_2(b)$ and $\Phi_3(c)$.

3 In the case of Φ_1 , grain boundaries are clearly visible in the implanted area and no gas bubbles were 4 formed near R_p (He) (Fig. 4a). SAED analysis (insert in Fig. 4a) confirmed that the material is still crystalline after 5 implantation. Nevertheless, some crystalline disorder is observed in SAED pattern $n^{\circ}1$ up to a depth of 265 nm ± 6 25 nm (white line). For Φ_2 (Fig. 4b), nanometric bubbles are visible near the R_p (see also Fig. 10). Smallest bubbles 7 $(\sim 1 \text{ nm})$ need a slight defocus to be better observed. These appear light in underfocus and dark in overfocus and 8 we assume these are full of helium and not voids. The irradiated area is completely amorphous up to a depth of 9 $265 \text{ nm} \pm 25 \text{ nm}$ (dash-dotted line in Fig. 4b), as indicated by the SAED pattern in Fig. 4b. Gas bubbles are also 10 visible on Fig. 4c (Φ_3) and their sizes vary from a few nm on both sides of the implantation profile, to a maximum 11 of ~ 100 nm in the area of maximum concentration. The bubble-containing band within the dotted lines is located 12 at a depth of between 50 and 370 nm (see also Fig. 6), and the center of gravity of the largest bubbles is at a depth 13 greater than the theoretical R_p calculated by SRIM, i.e. about 160 nm. The formation of large bubbles is responsible 14 for surface swelling as shown on the TEM micrograph in Fig. 5 taken near the boundary between the irradiated 15 and nonirradiated zones. The shift of implanted surface due to swelling with respect to the position of the non-16 implanted surface can reach 100 nm and this value gives a good indication of the height of the surface blisters 17 observed in Fig. 3c.





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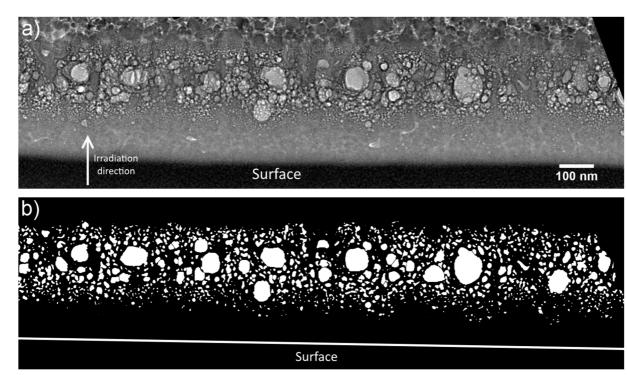
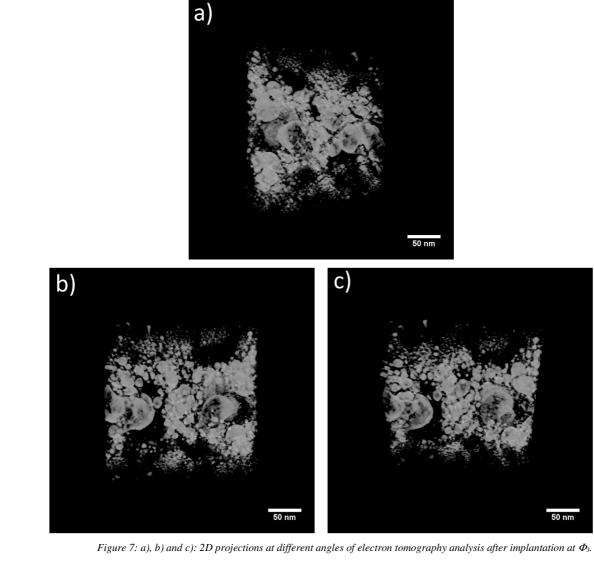


Figure 6: a) TEM image of SiC after helium RT-implantation Φ_3 and b) the corresponding binary image calculated using ImageJ software.

10 Measurement of bubble size as well as its eccentricity is difficult in this case because of the significant 11 superposition of bubbles in the thickness of the FIB cross-section (about 100 nm). From this segmentation, bubbles 12 have an average size of 9.2 ± 2.5 nm with a standard deviation of 9.3 nm. The latter reflects the large variety of 13 bubble size. In addition, the low image contrast makes it difficult to take into account bubbles smaller than 1 or 2 14 nm. The average bubble size is therefore certainly overestimated here. Furthermore, no reliable eccentricity value

- can be given, but from Fig. 6a, it appears that the bubbles appear to be relatively spherical. Therefore, both the
- superposition of the bubbles on the thickness of the cross-section and the relative sphericity of those are better
- visualized on Fig. 7a, b and c, obtained by electronic tomography.





3.2 Implanted area composition

STEM-EDX analysis of the implanted area was performed. No noticeable changes in composition were observed for Φ_1 (not shown) and the resulting elemental mapping for Φ_2 and Φ_3 is shown in Fig. 8 and 9, respectively.

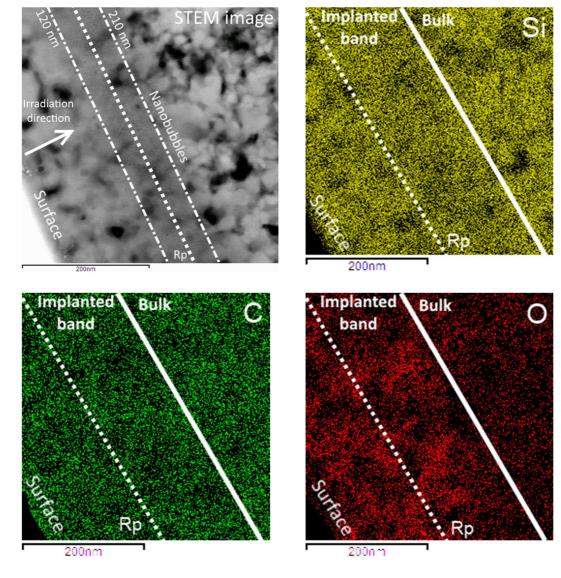
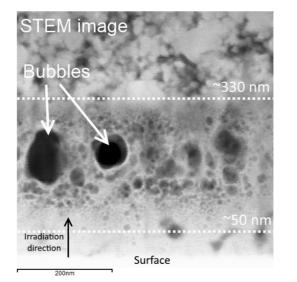
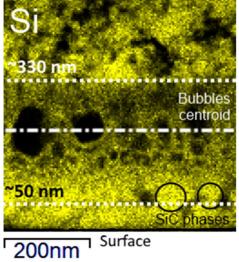




Figure 8: Elemental mapping of the implanted area obtained by STEM-EDX after helium irradiation at Φ_2 .





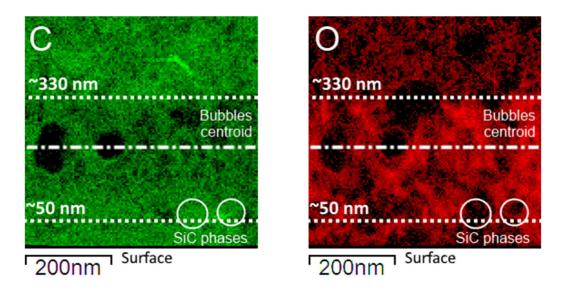


Figure 9: Elemental mapping of the implanted area obtained by STEM-EDX after helium irradiation at Φ_3 .

As can be seen from figures 8 and 9, the irradiation at Φ_2 and Φ_3 resulted in O-enrichment of the implanted area to a depth that also corresponds to the end of the band containing visible bubbles. This band extends from 120 to 210 nm for Φ_2 and from 50 to 330 nm for Φ_3 . However, some areas co-enriched in silicon and carbon and Odepleted still remain in the irradiated area (white circles in Fig. 9).

7 The theoretical helium profile at Φ₂ is superimposed on the STEM image in Fig. 10. The threshold of the
8 helium concentration above which bubbles are formed can be estimated. It is found to be close to 4.0 at. % ± 1 at.
9 %.

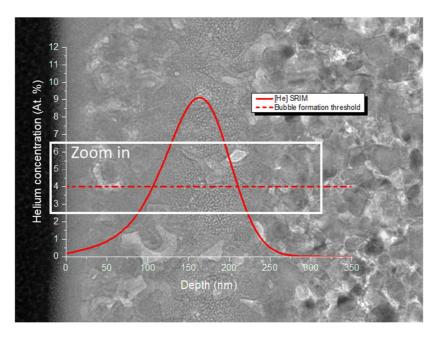
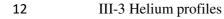
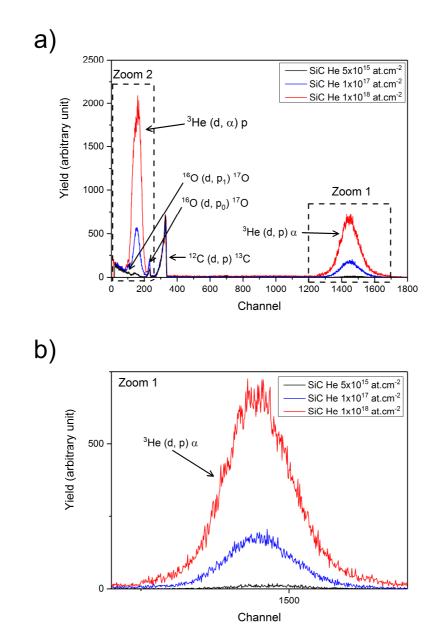




Figure 10: Superposition of the STEM micrograph and theoritical SRIM data at Φ_2 .



Nuclear reaction analysis spectra obtained for each fluence are given in Fig. 11. Fig. 11b and 11c show
 the zoomed in areas.



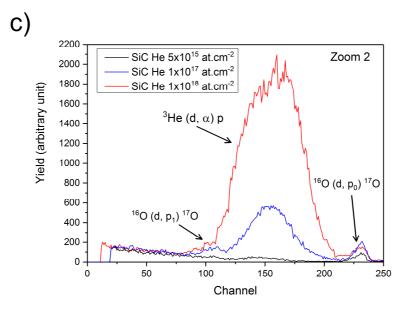


Figure 11: a) NRA spectrum for He implanted SiC, b) zoom on 3 He (d, p) 4 He reaction and c) zoom on low energy part of the spectrum

3 The signal corresponding to the ³He (d, p) ⁴He reaction (zoom 1) was integrated for the three fluences. 4 The experimental ratios Φ_{exp2}/Φ_{exp1} and Φ_{exp3}/Φ_{exp1} were found to be 20 ± 5 and 73 ± 5, respectively ($\Phi_{th2}/\Phi_{th1} =$ 5 20 and $\Phi_{th3}/\Phi_{th1} = 200$). In the region of the (d, α) peak a signal associated with (d, p) reactions on oxygen is 6 observed (Zoom 2). Indeed, the oxidation that was already visible on the STEM-EDX elemental mapping is 7 confirmed here for the highest fluences. The (d, α) peak was integrated and the experimental ratios were found to 8 be very close to the ones deduced previously from the ³He (d, p) ⁴He reaction i.e. 20 ± 5 and 69 ± 8 for Φ_{exp2}/Φ_{exp1} and Φ_{exp3}/Φ_{exp1} , respectively. If one considers that the intensity of the (d, p) signal at Φ_1 is associated with the 9 theoretical fluence of 5×10^{15} at.cm⁻², (no helium release expected at this fluence [47]), then Φ_{exp2} is close to 1×10^{17} 10 at.cm⁻² whereas a value of 3.64×10^{17} at.cm⁻² is found for Φ_{exp3} , i.e. nearly 36.4 % of the theoretical fluence Φ_{th3} 11 $(1 \times 10^{18} \text{ at.cm}^{-2}).$ 12

13 IV-Discussion

14 Helium irradiation at low fluence (Φ_1) does not cause material amorphization even at the dpa profile 15 maximum which places the threshold of amorphization above 0.16 dpa in our experimental conditions. A certain 16 degree of disorder is nevertheless created within the host matrix, symbolized by the visible halo on the 17 diffractogram in Fig. 4a. At higher doses (Φ_2 and Φ_3), there is total amorphization of the material over a large band 18 as expected for such dpa levels (see Fig. 1). The critical dose for amorphization in SiC at room temperature has 19 been reported to be ~ 0.3 dpa for 1.5 MeV Xe ions [48] (concordant with an earlier study [39]), and ~ 1.1-1.5 dpa 20 for 20-70 keV He ions [43, 49]. The trend for the increase in dpa dose required with decreasing incident projectile 21 mass, which has been reported previously by Snead et al. [50] is due to the decrease in residual chemical disorder 22 per ion impact. Thus, more displacement damage is required to produce amorphization with lighter projectiles.

Irradiation at room temperature and at high fluence leads to a considerable oxidation of the material. This phenomenon may seem enigmatic since the irradiation is conducted under a controlled secondary vacuum. Oxygen uptake increases with the irradiation fluence as it was also observed on samples irradiated by xenon at room 1 temperature in a previous study [39]. Quantitative NRA analysis of irradiated surfaces confirmed the link between

2 ion fluence and the uptake of oxygen by the material (Table 1).

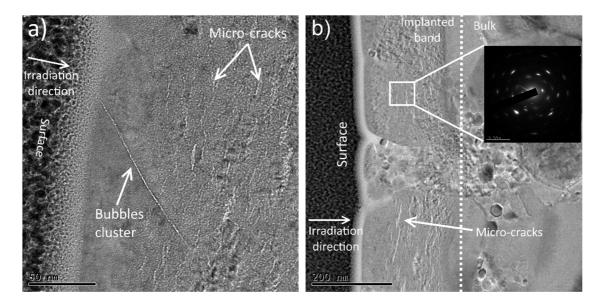
Theoretical fluence	Dpa _{max}	Experimental helium	Experimental oxygen
		fluence	fluence*
$\Phi_1^{\text{He}} = 5 \times 10^{15} \text{ at.cm}^{-2}$	0.16	$5 \times 10^{15} \text{ at.cm}^{-2}$	$< 3.40 \text{x} 10^{14} \text{ at.cm}^{-2}$
$\Phi_2^{\text{He}} = 1 \times 10^{17} \text{ at.cm}^{-2}$	3.26	1x10 ¹⁷ at.cm ⁻²	1.89x10 ¹⁷ at.cm ⁻²
$\Phi_3^{\text{He}} = 1 \times 10^{18} \text{ at.cm}^{-2}$	32.6	3.64x10 ¹⁷ at.cm ⁻²	2.97x10 ¹⁷ at.cm ⁻²

3

Table 1: Helium and oxygen fluences determined by nuclear reaction analysis. *NRA, Non-Rutherford cross-section [51]

4 The question of the source of oxygen at the origin of this chemical evolution is worth asking. Two main 5 hypotheses can be formulated according to whether one considers an "under beam" or "out of beam" oxidation. 6 Oxygen incorporation in 4H-SiC during hydrogen implantation was already underlined by Barcz et al. [52]. These 7 authors have shown that a cavity band near the end of range of hydrogen (or deuterium) tends to getter oxygen. 8 They concluded that the oxygen most likely penetrates from the ambient (gaseous O_2 and H_2O molecules) by 9 migrating from the sample edges along the heavily damaged and partially porous zone of damage produced by 10 hydrogen implantation. In our case, the entire implanted area is oxidized and not only the area with helium cavities. 11 It can be stipulated that the initial porosity of the material promotes the penetration of oxygen species that could 12 come from the secondary vacuum in the irradiation chamber, the latter can never be considered perfect. This 13 oxygen can also come partly from the oxide layer inevitably formed on the surface of SiC before irradiation. 14 Another possibility is that oxidation occurs just after irradiation when the sample is vented. Indeed, the atmosphere 15 then provides an abundant source of oxygen. A comprehensive study with a systematic parametric approach would 16 be required to highlight the mechanics and key parameters involved in this process.

17 Up to a fluence of 1×10^{17} at.cm⁻², no helium release was measured. However, a significant release of helium (about 70 %) was measured at the highest fluence Φ_3 . The remaining fluence of 3.64×10^{17} at.cm⁻² could 18 19 correspond to the saturation yield in our experimental conditions. Moreover, at this fluence, blisters form on the 20 surface (around 100 nm in size) due to the presence of large bubbles beneath the surface. A threshold concentration 21 of 4.0 at. $\% \pm 1$ at. % for the formation of helium bubbles was determined based on TEM observations. This value 22 is in good agreement with the value reported by Zinkle et al. [30]. On the other hand, Harrison et al. [43], did not 23 observed any He bubbles nucleation up to 5 dpa in the case of *in situ* experiments carried out on thin cross sections 24 (~ 100 nm thick) in a TEM with 20 keV He at RT. In the latter case, however, the very specific experimental 25 conditions perhaps explain such an apparent discrepancy. It is not clear whether oxidation, material amorphization 26 and bubble formation are correlated phenomena or not in the present study. However, an instructive comparison 27 can be done with another carbide (TiC) irradiated in similar conditions [40]. In this case, helium irradiation at Φ_3 28 result in the formation of micro- or nano-cracks beneath the surface near the projected range (Fig. 12). As indicated 29 by the SAED pattern, no amorphization occurred during ion implantation even if some disorder was present (insert 30 in Fig. 12b). The accumulation of defect and gas at depth induces here a fracturing of the material rather than the 31 formation of round bubbles. Almost no oxidation was measured in the irradiated TiC whatever the fluence. A 32 possible conclusion could thus be that material amorphization favors oxygen incorporation in the case of SiC but 33 this assumption may be confirmed by additional experiments (see next step below).



1 2

Fig. 12: TEM images of the TiC cross-section obtained by FIB after He RT-irradiation at a fluence of $\Phi_3 = 1 \times 10^{18}$ at.cm².

3 In Fig. 12a, a grain boundary is present which appears to be decorated with bubbles outside the implanted 4 He region by several tens of nanometers. Such segregation suggests enhanced He mobility in the grain boundary 5 compared to the crystalline matrix and these could play a role in the release path for the implanted gas. Indeed, 6 about 80% of helium is released from TiC after RT implantation at Φ_3 . This loss is higher than for SiC implanted 7 in similar conditions (about 70%). Note that the mechanism at the origin of helium release is still unclear in the 8 case of SiC. In Fig. 4c, most bubbles are located at a depth comprised between 100 and 340 nm. Almost no bubbles 9 are observed in the first 100 nm and the surface blisters are closed for the most part which prevents the formation 10 of visible outlets for the release of the gas. Bubble emptying is thus suspected, possibly including helium re-11 dissolution and a diffusion step through the amorphous SiC layer.

The next step of this work will consist in using different thermal treatments during implantation.
Irradiation experiments at temperatures between 300 and 1000 °C (to preserve SiC crystallinity) will be performed as a follow-up to this study. A similar protocol will be applied at RT and at high temperature on CVD deposits.
Indeed, the advantage of CVD technique (epitaxial growth) over HP or SPS sintering is that it allows a reproducible deposition of very fine microstructures (grain size << 100 nm and down to a few nanometers) without classical manufacturing bias: very high densification rate, no porosity and composition / quasi-perfect stoichiometry.</p>

18

19 V- Conclusion

20 β -SiC sintered bodies were implanted with 30 keV ³He ions at room temperature and up to an ion fluence of 21 1×10^{18} cm⁻². Nanometric bubbles are formed after irradiation at 10^{17} at.cm⁻² and the threshold concentration for 22 their formation is estimated at ~ 4.0 at. %. Virtually no helium release is measured below 10^{17} at.cm⁻² by NRA 23 technique For the highest fluence, the maximum size of bubbles reaches a hundred nanometers and surface 24 blistering is observed. Approximately 70% of the helium is released during implantation and the irradiated zone 25 also undergoes significant oxidation. The link between the microstructural evolution of the material, its progressive 26 oxidation under beam and the release of helium is discussed. The very likely role played by the porosity on the

- 1 oxidation of the material under irradiation at RT is underlined. Finally, a penetration of oxygen by migrating from
- 2 the porosities through the heavily damaged area seems to be the most likely hypothesis.
- 3

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- 9 received funding from the Euratom research and training programme 2014–2018 under grant agreement No.
- 10 633053. The views and opinions expressed herein do not necessarily reflect those of the European Commission.
- 11

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